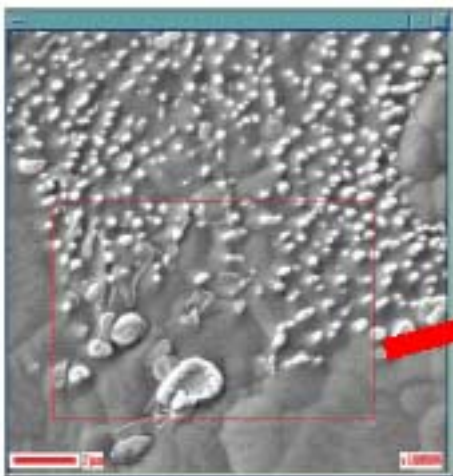


### Auger Image Collection from Defined Areas

Auger image collection from defined areas allows the operator to specify the location and size of analysis spot. Advantages of this feature are **speedy Auger image acquisition** from the target area and **higher resolution of Auger images**. Probe tracking is performed during image acquisition to correct the drift at the analysis site. The drift is detected from the image of the original area of view for accurate tracking and correction.

The figures below show secondary electron and Auger images of the area marked by the red line at higher resolution.



Secondary electron image  
(512 × 512 pixels)  
Sample: Lead free solder

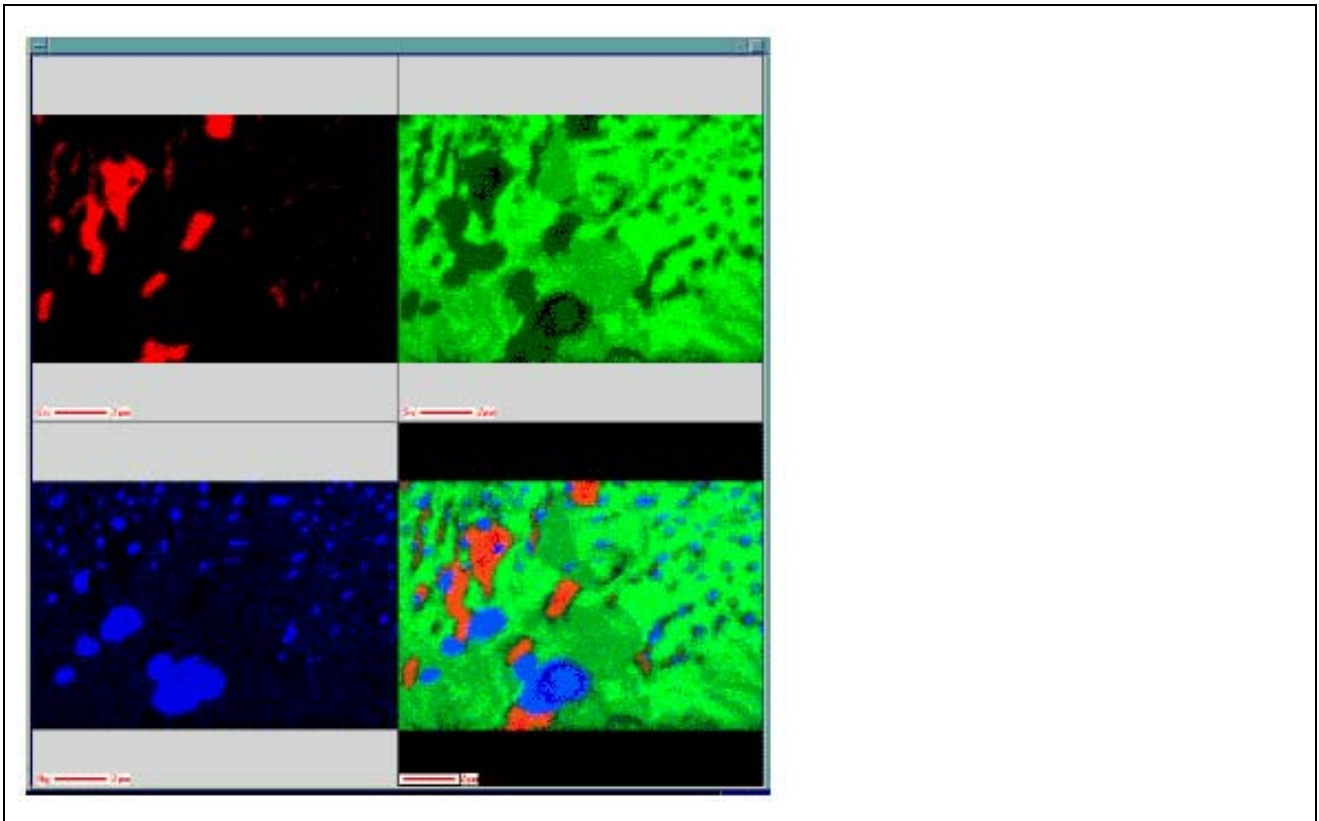


Secondary electron image of defined area  
(752 × 510 pixels)



Probe tracking  
Left: Target image  
Right: Image while Auger images are collected  
(Image drifting in the direction of the arrow; to be restored to the initial position with Image Shift)

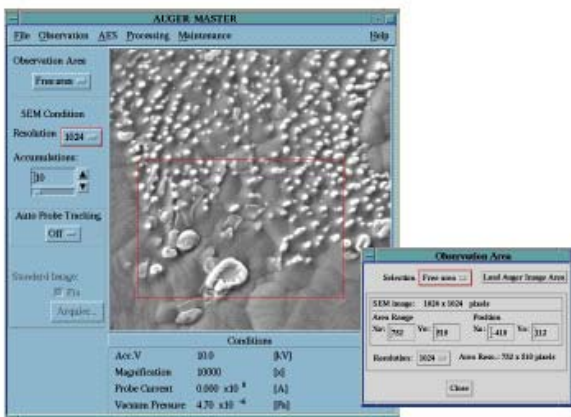
# JAMP Auger Micro Probe



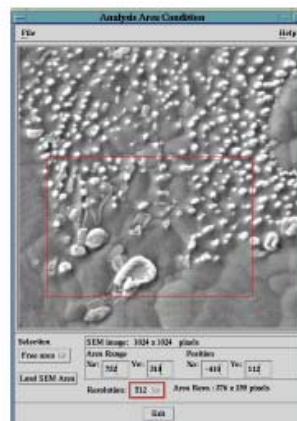
Auger images from defined area (376 × 255 pixels)  
 Top left: Cu Top right: Sn Bottom left: Ag Bottom right: RGB composite

The measurement time is reduced to 37% of the time needed for Auger image collection from the entire area of view (512 x 512 pixels).

The figures below show windows where an area of view is defined for secondary electron and Auger images. The same area of view may be defined in each window.



Selecting an area of view for SEI



Selecting an area of view for Auger image

**AES Software:** Supported in V4.01 or higher (OS: HP-UX 10.20 or higher\*)  
 \*Upgrade needed for HP-UX9.07 or earlier